

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Satoh et al.
Appl. No.	:	10/759,925
Filed	:	January 16, 2004
For	:	SEMICONDUCTOR PROCESSING WITH A REMOTE PLASMA SOURCE FOR SELF- CLEANING
Examiner	:	Michail Kornakov
Group Art Unit	:	1746

AMENDMENT AND RESPONSE TO OFFICE ACTION**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed on July 10, 2006, please amend the above-captioned application as follows. A one month extension of time is requested.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.